

Ville Miikkulainen

List of Publications by Year in descending order

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33
papers

1,873
citations

516215

16
h-index

360668

35
g-index

35
all docs

35
docs citations

35
times ranked

2851
citing authors

#	ARTICLE	IF	CITATIONS
1	Crystallinity of inorganic films grown by atomic layer deposition: Overview and general trends. Journal of Applied Physics, 2013, 113, .	1.1	1,190
2	Atomic Layer Deposition of Spinel Lithium Manganese Oxide by Film-Body-Controlled Lithium Incorporation for Thin-Film Lithium-Ion Batteries. Journal of Physical Chemistry C, 2014, 118, 1258-1268.	1.5	66
3	Controlling the Crystallinity and Roughness of Atomic Layer Deposited Titanium Dioxide Films. Journal of Nanoscience and Nanotechnology, 2011, 11, 8101-8107.	0.9	51
4	Atomic layer deposition of functional films for Li-ion microbatteries. Physica Status Solidi (A) Applications and Materials Science, 2014, 211, 357-367.	0.8	51
5	Atomic layer deposition of $\text{Li}_x\text{Ti}_y\text{O}_z$ thin films. RSC Advances, 2013, 3, 7537-7542.	1.7	49
6	Effect of corona pre-treatment on the performance of gas barrier layers applied by atomic layer deposition onto polymer-coated paperboard. Applied Surface Science, 2010, 257, 736-740.	3.1	47
7	Studies of the Electrochemical Behavior of $\text{LiNi}_{0.80}\text{Co}_{0.15}\text{Al}_{0.05}\text{O}_2$ Electrodes Coated with LiAlO_2 . Journal of the Electrochemical Society, 2017, 164, A3266-A3275.	1.3	43
8	Atomic Layer Deposition of Molybdenum Nitride from Bis(tert-butylimido)-bis(dimethylamido)molybdenum and Ammonia onto Several Types of Substrate Materials with Equal Growth per Cycle. Chemistry of Materials, 2007, 19, 263-269.	3.2	42
9	Electrical characterization of amorphous LiAlO_2 thin films deposited by atomic layer deposition. RSC Advances, 2016, 6, 60479-60486.	1.7	34
10	Nuclear reaction analysis for H, Li, Be, B, C, N, O and F with an RBS check. Nuclear Instruments & Methods in Physics Research B, 2016, 371, 211-215.	0.6	32
11	Bis(tert-butylimido)bis(dialkylamido) Complexes of Molybdenum as Atomic Layer Deposition (ALD) Precursors for Molybdenum Nitride: the Effect of the Alkyl Group. Chemical Vapor Deposition, 2008, 14, 71-77.	1.4	25
12	Thin films of MoN, WN, and perfluorinated silane deposited from dimethylamido precursors as contamination resistant coatings on micro-injection mold inserts. Surface and Coatings Technology, 2008, 202, 5103-5109.	2.2	22
13	Towards space-grade 3D-printed, ALD-coated small satellite propulsion components for fluidics. Additive Manufacturing, 2018, 22, 31-37.	1.7	21
14	Understanding the Stabilizing Effects of Nanoscale Metal Oxide and Metal Oxide Coatings on Lithium-Ion Battery Positive Electrode Materials. ACS Applied Materials & Interfaces, 2021, 13, 42773-42790.	4.0	18
15	Molybdenum nitride nanotubes. Thin Solid Films, 2008, 516, 6041-6047.	0.8	17
16	Atomic layer deposited lithium aluminum oxide: (In)dependency of film properties from pulsing sequence. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2015, 33, .	0.9	17
17	Atomic layer deposition of AlN using atomic layer annealing—Towards high-quality AlN on vertical sidewalls. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, .	0.9	15
18	Atomic Layer Deposition as Pore Diameter Adjustment Tool for Nanoporous Aluminum Oxide Injection Molding Masks. Langmuir, 2008, 24, 4473-4477.	1.6	14

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19	TiO ₂ Photocatalyzed Oxidation of Drugs Studied by Laser Ablation Electrospray Ionization Mass Spectrometry. <i>Journal of the American Society for Mass Spectrometry</i> , 2019, 30, 639-646.	1.2	12
20	Enhanced process and composition control for atomic layer deposition with lithium trimethylsilanolate. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2017, 35, .	0.9	11
21	Intercalation of Lithium Ions from Gaseous Precursors into δ -MnO ₂ Thin Films Deposited by Atomic Layer Deposition. <i>Journal of Physical Chemistry C</i> , 2019, 123, 15802-15814.	1.5	11
22	Synchronizing gas injections and time-resolved data acquisition for perturbation-enhanced APXPS experiments. <i>Review of Scientific Instruments</i> , 2021, 92, 044101.	0.6	11
23	(Invited) ALD of Thin Films for Lithium-Ion Batteries. <i>ECS Transactions</i> , 2011, 41, 331-339.	0.3	9
24	(Invited) Photo-Assisted ALD: Process Development and Application Perspectives. <i>ECS Transactions</i> , 2017, 80, 49-60.	0.3	9
25	Ambient pressure x-ray photoelectron spectroscopy setup for synchrotron-based in situ and operando atomic layer deposition research. <i>Review of Scientific Instruments</i> , 2022, 93, 013905.	0.6	9
26	Mono- and heterometallic carbonyl precursor based RuMo/Al ₂ O ₃ catalysts: hydrodesulfurization activity and temperature programmed studies. <i>Journal of Molecular Catalysis A</i> , 2001, 170, 209-218.	4.8	8
27	TiO ₂ Photocatalysisâ€”DESI-MS Rotating Array Platform for High-Throughput Investigation of Oxidation Reactions. <i>Analytical Chemistry</i> , 2017, 89, 11214-11218.	3.2	7
28	Photoassisted atomic layer deposition of oxides employing alkoxides as single-source precursors. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2019, 37, .	0.9	7
29	Ionic conductivity in Li _x TaO _y thin films grown by atomic layer deposition. <i>Electrochimica Acta</i> , 2020, 361, 137019.	2.6	6
30	Highly Material Selective and Self-Aligned Photo-Assisted Atomic Layer Deposition of Copper on Oxide Materials. <i>Advanced Materials Interfaces</i> , 2021, 8, 2100014.	1.9	6
31	Constructing Spacecraft Components Using Additive Manufacturing and Atomic Layer Deposition: First Steps for Integrated Electric Circuitry. <i>Journal of Aerospace Engineering</i> , 2021, 34, .	0.8	6
32	Atomic Layer Deposited Hybrid Organic-Inorganic Aluminates as Potential Low-k Dielectric Materials. <i>Materials Research Society Symposia Proceedings</i> , 2015, 1791, 15-20.	0.1	2
33	(Invited) Photo-Assisted ALD: Process Development and Application Perspectives. <i>ECS Meeting Abstracts</i> , 2017, , .	0.0	1